**Counteracting Trapped Ion Effects in the HESR** 

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# Panda Target and Spectrometer

**Beam Envelopes** 



**Potential Well of the Antiproton Beam** 

Central Potential Depth

$$U(s) = U(0, 0, s) = \frac{\lambda}{4\pi\epsilon_0} \left[ \gamma + \ln\left(\frac{2r_c^2}{(\sigma_x + \sigma_y)^2}\right) \right], \quad (1)$$

Transverse Electric Field near Beam Center

$$E_x(x,y) = \frac{\lambda}{2\pi\epsilon_0} \frac{1}{(\sigma_x + \sigma_y)} \frac{x}{\sigma_x}$$
$$E_y(x,y) = \frac{\lambda}{2\pi\epsilon_0} \frac{1}{(\sigma_x + \sigma_y)} \frac{y}{\sigma_y}.$$
(2)



Central beam potential U(s) assuming the standard optics,  $L_1=0.9C$ ,  $p_{\bar{p}}=15~{\rm GeV/c}$ ,  $N_{\bar{p}}=1.0\cdot10^{11}$  and  $\eta=0$ .

### **Transverse Electric Field of the Beam**

Clearing electrodes near the inner surface of the beam tube

Clearing electric field: 2250 V/m

Clearing electrodes every 5 m and near potential minima



Upper limit  $E_{max}$  of the transverse electric field of the antiproton beam assuming the standard optics,  $L_1 = 0.9C$ ,  $p_{\bar{p}} = 15 \text{ GeV/c}$  and  $N_{\bar{p}} = 1.0 \cdot 10^{11}$ .

#### **Longitudinal Electric Field**

Longitudinal Electric Field  $E_{s}{\rm ,}$  Longitudinal Acceleration  $a_{s}{\rm ,}$  Clearing Time  $T_{c}$ 

$$E_s = -\frac{U_{i+1} - U_i}{s_{i+1} - s_i}$$
(3)

$$a_s = \frac{e}{m} E_s \tag{4}$$

$$T_c = \sqrt{\frac{2l}{a_s}}.$$
(5)



Longitunal electric field component  $E_s$  of the antiproton beam assuming the standard optics,  $L_1 = 0.9C$ ,  $p_{\bar{p}} = 15 \text{ GeV/c}$  and  $N_{\bar{p}} = 1.0 \cdot 10^{11}$ .

**Production Time, Clearing Time and Neutralization** 

Production Rate  $R_{p,i}$  and Production Time  $T_{p,i}$  of lon i

$$R_{p,i} = \sigma_i \rho_{m,i} \beta c. \tag{6}$$

$$T_{p,i} = \frac{1}{R_{p,i}}.$$
(7)

Clearing Rate  $R_{c,i}$  and Clearing Time  $T_{c,i}$ 

$$T_{c,i} = \frac{1}{R_{c,i}}.$$
(8)

Local Neutralization  $\eta_i(s)$ 

$$\eta_i(s) = \frac{L_1}{C} \frac{T_{c,i}(s)}{T_{p,i}(s)} = 0.9 \frac{T_{c,i}(s)}{T_{p,i}(s)}.$$
(9)

$$\eta(s) = \sum_{i=1}^{n} \eta_i(s) \tag{10}$$

### lonization

Ionization Cross Section (Bethe's Formula)

$$\sigma = 4\pi \left(\frac{\hbar}{m_e c}\right)^2 \left\{ M^2 \left[\frac{1}{\beta^2} \ln \left(\frac{\beta^2}{1-\beta^2}\right) - 1\right] + \frac{C}{\beta^2} \right\}, \quad (11)$$

$$4\pi \left(\frac{\hbar}{m_e c}\right)^2 = 1.874 \cdot 10^{-24} \text{ m}^2.$$
 (12)

#### Ionization cross sections

$p_{ar{p}}~({\sf GeV/c})$	$\sigma({ m H_2})~({ m m^2})$	$\sigma({ m CH}_4)~({ m m}^2)$	$\sigma({ m H_2O})~({ m m^2})$	$\sigma({ m CO})~({ m m}^2)$
1.500	$2.16 \cdot 10^{-23}$	$1.12 \cdot 10^{-22}$	$8.60 \cdot 10^{-23}$	$9.37 \cdot 10^{-23}$
3.825	$1.87 \cdot 10^{-23}$	$9.88 \cdot 10^{-23}$	$7.61 \cdot 10^{-23}$	$8.35 \cdot 10^{-23}$
8.889	$2.00\cdot 10^{-23}$	$1.07 \cdot 10^{-22}$	$8.27 \cdot 10^{-23}$	$9.11 \cdot 10^{-23}$
15.000	$2.12 \cdot 10^{-23}$	$1.15 \cdot 10^{-22}$	$8.84 \cdot 10^{-23}$	$9.78 \cdot 10^{-23}$

Ionization Rate

$$\frac{dN_{ion}}{dt} = \sigma N_{\bar{p}} f \rho_m C = N_{\bar{p}} \sigma \rho_m \beta c.$$
(13)

With  $N_{ar{p}} = 1.0 \cdot 10^{11}$  at 15 GeV/c and  $ho_m({
m H_2}) = 2.47 \cdot 10^{13} {
m m}^{-3}$ 

$$\frac{dN_{ion}}{dt} = 1.57 \cdot 10^{10} \text{ s}^{-1}.$$
 (14)

 $p = 1.0 \cdot 10^{-9}$  mbar: Full neutralization within 6.4 s (if no clearing)!

### **Residual Gas Pressure and Production Time** $T_p$



Vacuum pressure p(s) without NEG coating and heating jackets in the arcs.



#### **Continuous Clearing Electrodes**



A 0.1 mm thin and 30 mm wide isolating  $Al_2O_3$  layer can be deposited at the bottom of the beam pipe using plasma spraying. On top of the isolating layer a 25 mm wide highly resistive thick film coating with a few 10  $\mu$ m thickness is applied. The highly resistive coating on top of the dielectric can be realized using commercially available thick film pastes from Heraeus. Reference: Fritz Caspers (CERN)

The surface resistance  $R_{surface}$  of the highly resistive layer must be higher than the free space impedance  $Z_0 = 377 \ \Omega$  but small enough that the voltage drop along the electrode is not too high. If  $R_{surface} \gg Z_0$  the layer is "invisible" to the electromagnetic waves and the longitudinal and transverse impedance budget is not seriously affected!

The length of such an electrode can be a few meters. It can be installed in straight sections and in magnetic dipole sections. The clearing voltage can be applied by feedthroughs at one or both ends of the electrode. Clearing voltages up to -1.0 kV are possible. Clearing voltage of -1.0 kV yields electric fields of -640 V/m in the center of a 89 mm wide beam pipe.

# **Continuous Clearing Electrodes**





# Panda Target and Spectrometer

### **Pressure Profile Cluster-Jet**



**Pressure Profile Pellet Target** 



# **Continuous Clearing Electrodes near Panda**



# **Continuous Clearing in a Solenoid**



# Neutralization $\eta(s)$ : Single vs. Continuous Clearing



### **Electron Cooler**

- 1. Kinetic energy of electrons: 0.45 4.5 MeV
- 2. Momentum range of antiprotons: 1.5 8.9  ${\rm GeV/c}$
- 3. Electron current: 1.0 A
- 4. Magnetic field of solenoid: 0.2 T
- 5. Field straightness:  $B_r/B < 10^{-5}$
- 6. Length: 24 m

#### **Drawbacks of the EC: Space-Charge Potential**



Space charge potential U(r) of the electron beam ( $I_e = 1.0$  A, a = 5 mm,  $r_c = 100$  mm). Full line: Beam neutralization  $\eta = 0.0$ . Dashed line: Beam neutralization  $\eta = 0.9$ . Left: Nominal kinetic energy 0.45 MeV. Right: Nominal kinetic energy 4.5 MeV.



Variation of the electron energy due to the space-charge potential U(r)

#### **Neutralization Electrodes for EC**



Neutralization electrodes at entrance and exit of EC as used at LEAR: Instead of extracting the ions which are produced by ionization of the residual gas in the EC, the ions are reflected and stored in the EC.

The optimum neutralization is reached if  $\eta=1/\gamma_e^2.$ 

The continuously produced surplus ions can be removed by shaking the ions with a sine-wave signal applied to a transverse kicker ('LEAR shaker').

#### **Summary and Conclusions**

- 1. Ionization of Residual Gas Molecules
- 2. Single vs. Continuous Clearing Electrodes
- 3. Continuous Clearing Electrodes in the Dipoles
- 4. Continuous Ion Clearing near Panda Target
- 5. Electron Cooler: Optimum Neutralization  $\eta = 1/\gamma_e^2$